

WHAT IS CLAIMED IS:

1. A method of manufacturing comprising the steps of:  
providing a manufacturing system including at least one manufacturing process therein;  
providing a human interface device operatively connected to said manufacturing system and including:  
at least a first station associated therewith;  
at least a second station associated therewith;  
at least a first display device associated therewith;  
providing at least one object and at least one article corresponding to said at least one object;  
introducing said at least one article into said manufacturing system;  
placing said at least one object onto said at least a first station of said human interface device; and  
thereafter advancing said object to said second station of said human interface device in response to said at least a first display device.
2. The method of claim 1 wherein said manufacturing system comprises a photolithographic integrated circuit manufacturing system.
3. The method of claim 1 wherein said at least one manufacturing process includes a wafer stepper machine.
4. The method of claim 1 wherein said at least one manufacturing process includes both a resist spin track machine and a wafer stepper machine.
5. The method of claim 4 wherein said at least a first station corresponds to said resist spin track machine and said at least a second station corresponds to said wafer stepper machine.

6. The method of claim 1 further including the steps of:

providing at least a third station associated with said human interface device;

5 providing at least a second display device associated with said human interface device;

advancing said object to said third station of said human interface device in response to said at least at least a second display device.

7. The method of claim 1 wherein said at least one object is a container and said step of introducing said at least one article into said manufacturing system includes removing said at least one article from said  
5 container.

8. A method of manufacturing comprising the steps of:

providing a manufacturing system including at least one manufacturing process therein;

5 providing a human interface device operatively connected with said manufacturing system;

providing at least one object located at said at human interface device;

10 determining a first item of information by scanning at least a portion of said at least one object;

obtaining at least one parameter depending upon said first item of information; and

adjusting said at least one process according to said at least one parameter.

9. The method of claim 8 wherein said step of determining a first item of information by scanning at least a portion of said at least one object comprises scanning a barcode label on said at least a portion of  
5 said at least one object with a barcode scanning device.

10. The method of claim 8 wherein said manufacturing system comprises a photolithographic integrated circuit manufacturing system.

11. The method of claim 8 wherein said at least one manufacturing process includes a wafer stepper machine.

12. The method of claim 8 wherein said at least one manufacturing process includes both a resist spin track machine and a wafer stepper machine.

5                      13. A manufacturing system for manufacturing integrated circuit devices comprising:  
                             at least a first manufacturing machine;  
                             a human interface device including:  
                                 at least a first station associated therewith;  
                                 at least a first display device located adjacent said first station; and  
                                 at least a first scanning device located adjacent said first station;  
10                      a first controller operatively connected to both said first display device and said first scanning device;  
                             a second controller operatively connected to said at least a first manufacturing machine; and  
                             a data link connecting said first controller and  
15                      said second controller.

14. The manufacturing system of claim 13 wherein said system comprises a photolithographic integrated circuit manufacturing system.

15. The manufacturing system of claim 13 wherein said at least a first manufacturing machine comprises a wafer stepper machine.

16. The manufacturing system of claim 15 and further comprising:

at least a second station associated with said human interface device;

5 at least a second display device located adjacent said at least a second station;

at least a second scanning device located adjacent said second station;

10 wherein said first controller is operatively attached to both said second display device and said second scanning device.

17. The manufacturing system of claim 16 further comprising:

at least a second manufacturing machine;

5 a third controller operatively connected to said at least a second manufacturing machine; and

a data link connecting said first controller and said third controller.

18. The manufacturing system of claim 17 wherein said second manufacturing machine is a resist spin track machine.